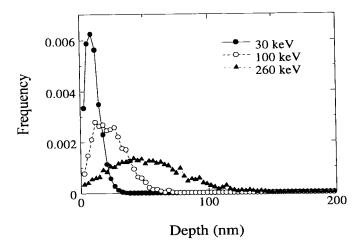
Title: METHOD OF
MANUFACTURING NANO-GAP
ELECTRODE
Inventor(s): Takashi NAGASE et. al.

Appl. No.: Unassigned

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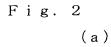
F i g. 1

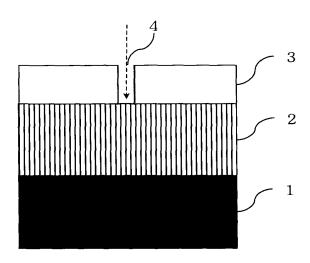


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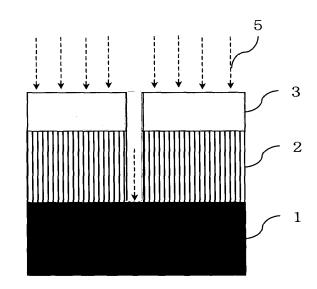
Appl. No.: Unassigned

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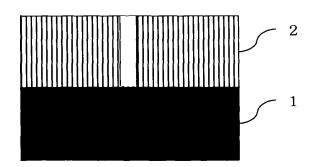




(b)



(c)

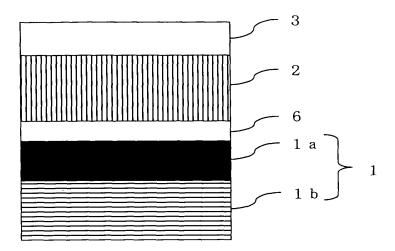


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 $3 \nearrow 5$

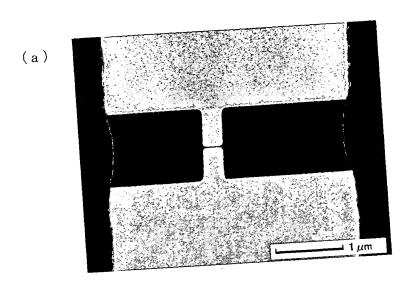
Fig. 3

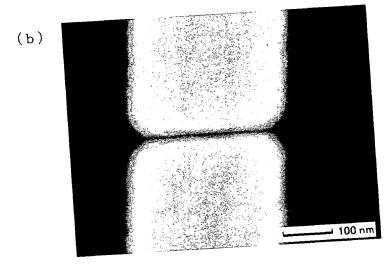


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F i g. 4





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